

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Gabric, *et al.* Docket No.: INF 2006 VJ 33543 US
Serial No.: 10/586,788 Art Unit: 2893
Filed: September 2, 2008 Examiner: Nikolay K. Yushin
Title: Plasma Excited Chemical Vapor Deposition Method, Silicon/Oxygen/Nitrogen-Containing-Material and Layered Assembly

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Dear Sir:

The Applicants wish to bring to the attention of the U.S. Patent and Trademark Office the information noted on the enclosed forms PTO/SB/08a and 08b, which may be considered material to the examination of the above-identified application. Copies of the U.S. Patents and Publications cited are not being submitted, however Applicants have included copies of the foreign patents and non-patent literature.

This Information Disclosure Statement is submitted under 37 C.F.R. §1.97(c) together with a \$180.00 fee under 37 C.F.R. §1.17(p) after the C.F.R. §1.97(b) time period, but before final action or notice of allowance, whichever occurs first.

Please charge the required fee of \$180.00 and any additional amount, or credit any overpayment to Deposit Acct. No. 50-1065 of the below mentioned firm.

Respectfully submitted,



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11/4/09
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